

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): KATSUMATA et al.	Atty. Dkt.: 01-570
Serial No.: Unknown	Group Art Unit:
Filed: Concurrently herewith	Examiner:
Title: METHOD OF MANUFACTURING SEMICONDUCTOR PRESSURE SENSOR	

Commissioner for Patents
Arlington, VA 22202

Date: March 4, 2004

INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §1.56, the reference(s) listed on the attached Form PTO-1449 is/are submitted for consideration by the Examiner without any admission that it/they constitute(s) statutory prior art, or without any admission that it/they contain(s) subject matter that anticipates the invention or renders the invention obvious to a person of ordinary skill in the art.

The Examiner is requested to initial the attached PTO Form-1449 and to return a copy of same to the undersigned attorney as proof that the listed reference(s) has/have been considered and made of record.

Respectfully submitted,



David G. Posz
Reg. No. 37,701

Posz & Bethards, PLC
11250 Roger Bacon Drive, Suite 10
Reston, VA 20190
(703)707-9110 (phone)
Customer No. 23400

FORM PTO-1449	ATTY. DKT NO.	01-570	SER. NO.
	APPLICANT KATSUMATA et al.		
	FILING DATE	March 4, 2004	GROUP

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS
		6,601,452 (English counterpart of JP-A-2001-356061 which is discussed in page 1)	Aug. 5, 2003	Murata et al.		
		6,595,065 (English counterpart of JP-A-H11-94666 which is discussed in pages 2)	Jul. 22, 2003	Tanizawa et al.		

FOREIGN PATENT DOCUMENTS

TRANSLATION

		DOCUMENT NUMBER	DATE	COUNTRY	NAME	CLASS	SUB CLASS	YES	NO	
										Eng. Abstract
		JP-A-H01-261872	10/18/89	JAPAN						X
		JP-A-H09-18016	1/17/97	JAPAN						X

* Full English text is available in machine-translated form in JPO (Japanese Patent Office) English language web site at <http://www1.ipdl.jpo.go.jp/PA1/cgi-bin/PA1INDEX>.

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, etc.)

EXAMINER		DATE CONSIDERED